

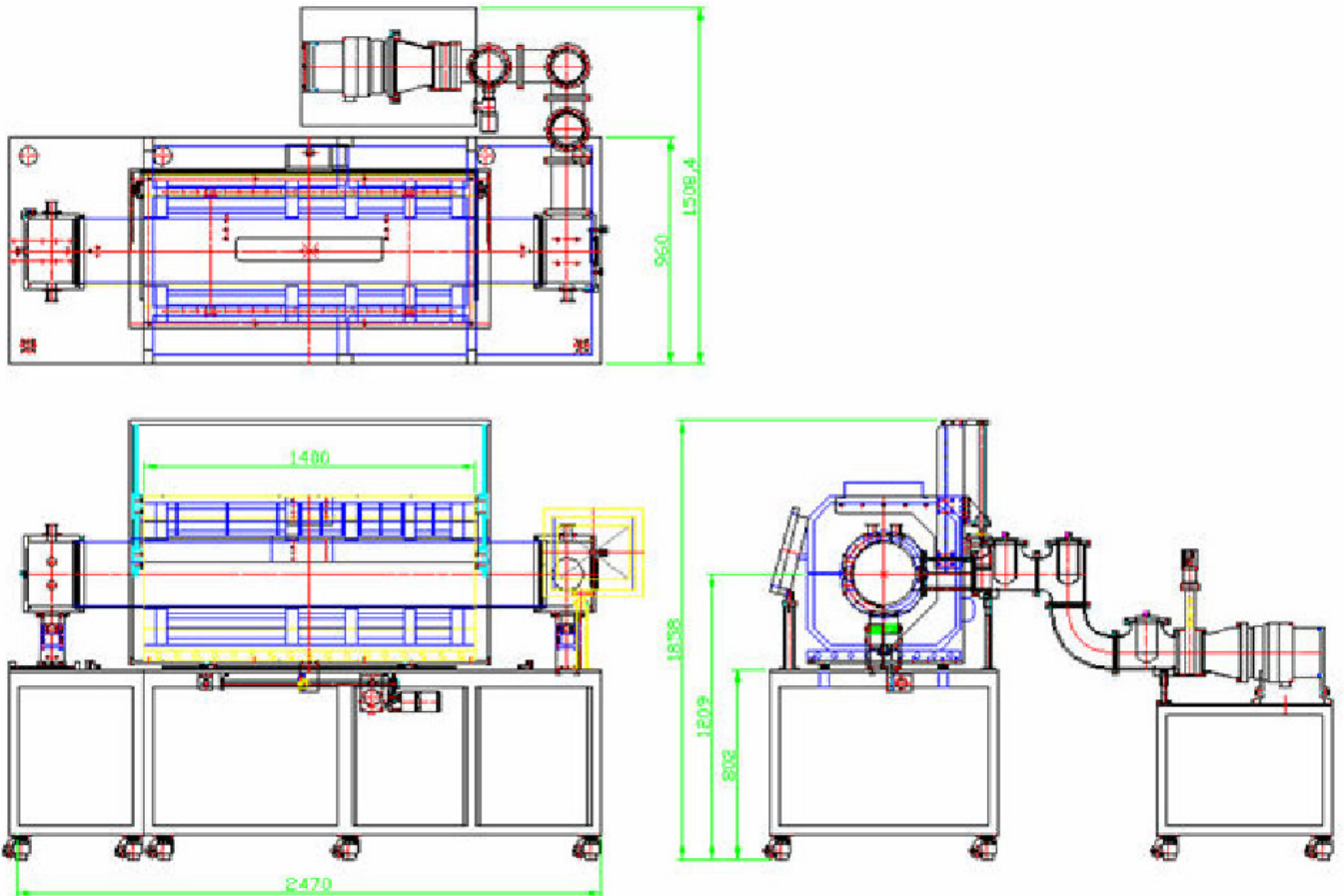
ATS-Furnace Series Vacuum Furnace for Display Materials Purification



Special Features

- ◆ Economic standard sputter system for R&D and small mass production
- ◆ Two tiltable 4" sputter guns and one extra sputter gun port
- ◆ Quartz tube conveniently exchangeable
- ◆ Plug system movable in x, y, z direction
- ◆ Process range
400 ~ 900℃
- ◆ Operated by PLC touch screen
- ◆ Applications
display materials purification
differential evaporation of organic materials
- ◆ Wafer capacity
100 × 8"
- ◆ Average throughput
Up to 30,000 wafers per year
- ◆ Dimension
2,500L × 1,500H × 6,00W (mm³)
- ◆ Others
Power: AC 220V, 2 phase
Gas : N₂/Ar
Heater : KT APM molding heater (kanthal)
(heating rate: 10℃/min, max.
temp.:1000℃, deviation: negligible)
Pump: rotary(600l/min) & turbo(350l/s)

◇ Layout



175-25, Cheongcheon-Dong 2, Bupyeong-Gu,

Incheon, 403-853, Rep. Korea

Phone: +82-32-508-8060/8067

Fax: +82-32-508-8069

E-mail: atech@atechsystem.co.kr

Website: www.atechsystem.co.kr